## A=2=6 $\,$ Soft-Error Analysis Of Fully Static MOS RAM $\,$

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A static MOS RAM cell with polysilicon resistive load (>50Mohm) has been analyzed with respect to an alpha-particle induced soft-error phenomenon. The cell design for minimizing the soft-error rate has been obtained from the analysis of effective critical charge Q<sub>crit</sub>.

The static RAM cells having high impedance loads shown in Fig.l suffer from the soft-error problem as do the dynamic RAM cells. The model of soft-error process is expressed in the VL-V2 plane as shown in Fig.2, where  $\Gamma_0(\Gamma'_0; \text{RL}\cdot\text{Cl}\neq\text{R2}\cdot\text{C2})$ 

is the line which indicates the unstable equilibrium points. The points Pl and P2 indicate the stable states when Tr.l and Tr.2 are in the off-state. The stable points are Ql and Q2 in a read out operation. The cell state is originally at the point I in Fig.2. When enough electrons are injected into a storage node which is in the high voltage level  $V_{\rm H}$ , the storage node voltage is reduced and the cell state moves from the point I to P2 through the point A, B and C. The voltage of "L" storage node is also lowered in the amount of  $V_{\rm OL}$  by the electron injection or C-coupling between the "H" and "L" storage node. The effective critical charge  $Q_{\rm crit}$  which is defined as the amount of collected charge in "H" storage node when the soft-error occurs is written as follows;

 $Q_{\text{crit}} = (\text{Cl+C3}) \cdot (V_{\text{H}} - \text{Vth}) + (\text{Cl+}\frac{\text{C2} \cdot \text{C3}}{\text{C2+C3}}) \cdot (\text{Vth-}V_{\Gamma} + V_{\alpha L} \cdot (1 - \frac{V_{\Gamma}}{\text{Vth}})) \quad ---- \quad (\text{Eq.l}),$ 

where  $V_{\Gamma}$  is the voltage Vl at the cross point of  $\Gamma_0^{\prime}$  and x-axis. ( $V_{\Gamma}=0$ ;Rl·Cl=R2·C2) A tiny compensation current(<0.1µA) through the polysilicon resistor is neglected.

The value of  $V_{\rm H}$  is kept to Vcc in the data retention mode. However, in the active mode,  $V_{\rm H}$  lowering is unavoidable after not only the write operation but also the read operation, especially, in the high density and high speed design. Every time a row select line is charged up,  $V_{\rm H}$  falls to the stable level  $V_{\rm R}$  in the read out operation and rises to Vcc level with a large time constant. This  $V_{\rm H}$  lowering reduces  $Q_{\rm crit}$ , consequently enhances the soft-error rate in the shorter cycle time operation. Fig.3 shows the cycle time dependence of the error-rate. The error-rate is decreased and saturated with increasing the cycle time. In practical operations, the error-rate increases with higher  $R_{\rm H}$ , but it does not depend on  $R_{\rm H}$  in the long cycle operation. Fig.4 shows the dependence of the error-rate has a strong dependence on Vcc for the lower  $R_{\rm H}$  or the longer cycle time. It is less dependent on  $R_{\rm H}$  in the longer cycle time, range.

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Eq.1 also suggests the relation ship between the cell layout and the error-rate. The increase of  $V_{\alpha_{\rm L}}$  results in the increase of  $Q_{\rm crit}$ . On the other hand, the imbalance of two pull-up resistors increases  $V_{\Gamma}$  and cancels the  $V_{\alpha_{\rm L}}$  effect so that  $Q_{\rm crit}$  is reduced, effectively. From these consideration, a high tolerance cell against the soft-error has been designed according to the following items ; (1) Individual two storage N<sup>+</sup> regions were placed closely, which enlarged  $V_{\alpha_{\rm L}}$ . (2) The pull-up devices were formed on a flat field oxide region, which balanced two pull-up resistors. (3) The area ratio of N<sup>+</sup> storage region to other N<sup>+</sup> region were made as small as possible, which reduced the collection efficiency of electrons. Fig.5 shows the comparison of the error-rate between the present cell and another cell<sup>1</sup> which fabricated by double polysilicon technology and had about twice as large as storage capacitance. The alpha-particle endurance of present cell has been improved 10 to 100 times in spite of the storage capacitance disadvantage.

The experimental results show a good agreement with the above mentioned model for the soft-error of the static MOS RAM.



Fig.l Memory cell circuitry.



Fig.2 V1-V2 plane which shows states of memory cell.



Ref. 1) K.Anami et al. ; ISSCC DIJEST OF TECHNICAL PAPERS, p.250-251; Feb., 1982.